

Amendment

J.C. PATENTS
4 VENTURE, SUITE 250
IRVINE, CALIFORNIA 92618
TEL.: (949) 660-0761
FAX: (949) 660-0809
E-MAIL: jcpi@email.msn.com

1765

FAX TRANSMISSION SHEET

January 15, 2004

Our Ref : MART4591-R
Appl. No. : 09/759,899
Filing Date : January 12, 2001
Pages : Cover + 6

BY FACSIMILE ONLY

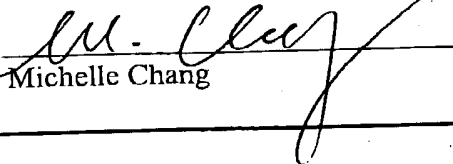
FAX : 703-308-6778
ATTN : Mr. George Allen
United States Patent and Trademark Office
FROM : Jiawei Huang, Reg. No.: 43,330

MESSAGE : Enclosed herewith is copy of the amendment filed on 03/11/2003.

Sir:

I hereby certify that this correspondence is being facsimile transmitted to the Patent and Trademark Office on January 15, 2004 at the above indicated fax number.

Sign by:


Michelle Chang

Note: This facsimile transmission is intended only for the use of the individual or entity to which it is addressed, and may contain information that is privileged, confidential and exempt from disclosure under applicable law. If the reader is not the intended recipient, or the employee or agent responsible for delivering the message to the intended recipient, you are hereby notified that any dissemination, distribution or copying of this communication is strictly prohibited. If you have received this transmission in error, please kindly notify us immediately, and return the original message to us at the above address. We greatly appreciate your cooperation.

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of :

Application No. : 09/759,899

Filed : January 12, 2001

For : TREATMENT ON SILICON OXYGNITRIDE

Applicant : I. T. Chen

Examiner : Ahmed, Shamim

Art Unit : 1765

No fee is believed to be due. However, the Commissioner is authorized to charge any fees required in connection with the filing of this paper to account No. 50-0710 (Order No. MART4591).

AMENDMENT AND RESPONSE TO OFFICE ACTION

BOX Non-Fee Amendment

Assistant Commissioner of Patents and Trademarks
Washington, DC 20231

Dear Sir:

The Office Action mailed on December 12, 2002 has been carefully considered. In response thereto, please enter the following amendments and consider the following remarks.

In The Title:

Please substitute the following clean copy title for the pending title:

--METHOD TO REMOVE SILICON OXIDE MATERIAL GENERATED DURING
REMOVAL OF PHOTORESIST--